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Misaizu et al.

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(54) **STRAIN GAUGE**

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(**) Term: **15 Years**

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(30) **Foreign Application Priority Data**

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(52) **U.S. CL.**
USPC **D10/102; D10/83**

(58) **Field of Classification Search**

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D10/52, 61, 106.1, 109.1, 123; D14/455,
D14/456

CPC B60K 2001/003; B60K 5/04; G01P 1/02;
G01P 1/07; G01P 1/12; G01P 3/02; G01P
3/26; G01P 3/64; G01P 9/00; G01D 1/04;
G01L 1/04; G01L 1/08; G01L 1/10;
G01L 1/12; G01L 1/14; G01L 3/00;
G01L 7/00; G01L 1/2287; G01L 1/16;
B32B 1/00; B32B 5/00; B32B 27/281;
B32B 15/43; G01B 7/16; G01N 27/223;
G01M 5/0091

See application file for complete search history.

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(57) **CLAIM**

The ornamental design for a strain gauge, as shown and described.

DESCRIPTION

FIG. 1 is a top plan view of a strain gauge, showing our new design;

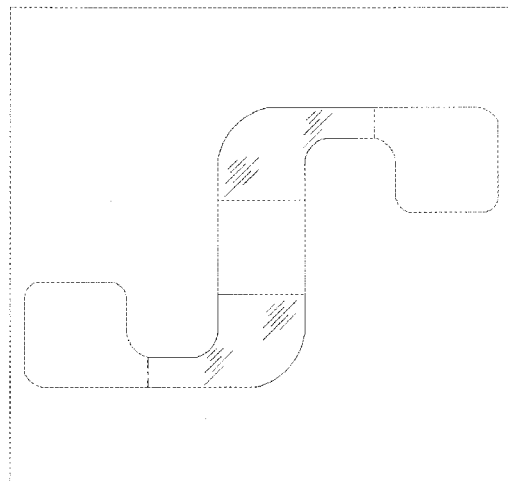
FIG. 2 is a front view thereof;

FIG. 3 is a right side view thereof; and,

FIG. 4 is a bottom plan view thereof.

The broken lines and the uneven-length broken lines shown in the drawings represent portions of the strain gauge that form no part of the claimed design. All sides not shown form no part of the claimed design.

1 Claim, 2 Drawing Sheets



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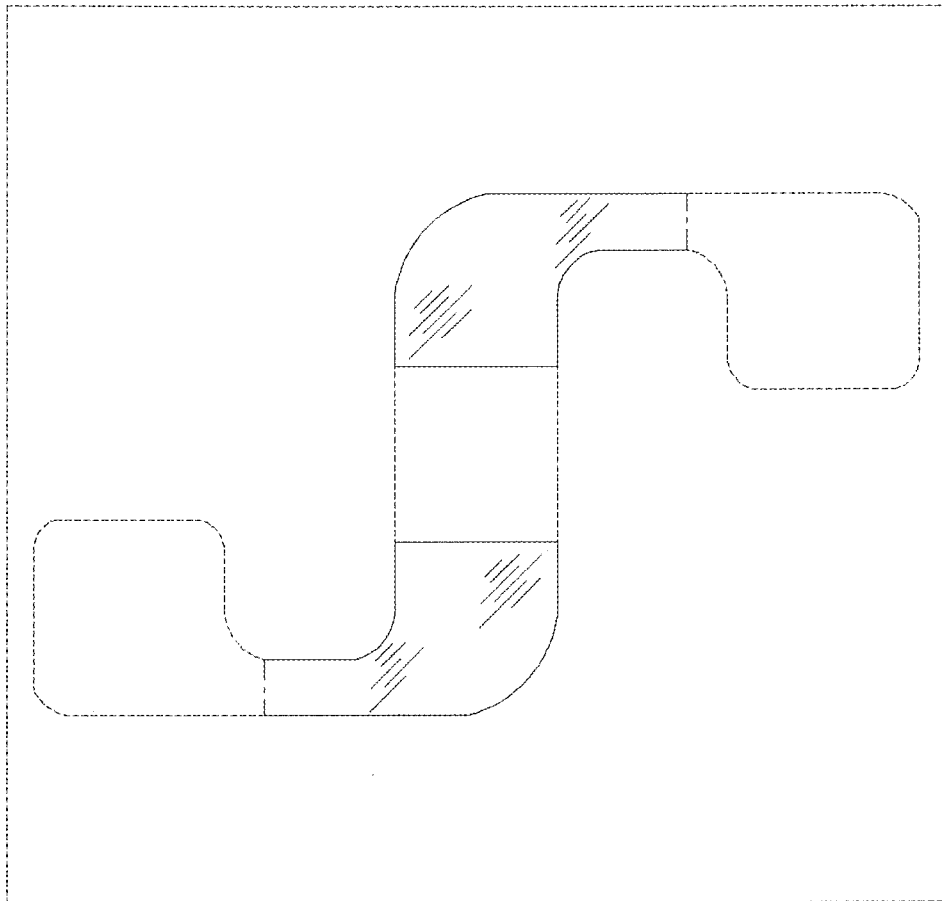


Fig. 1

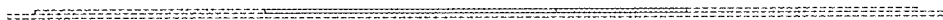


Fig. 2

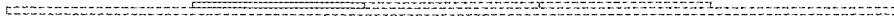


Fig. 3

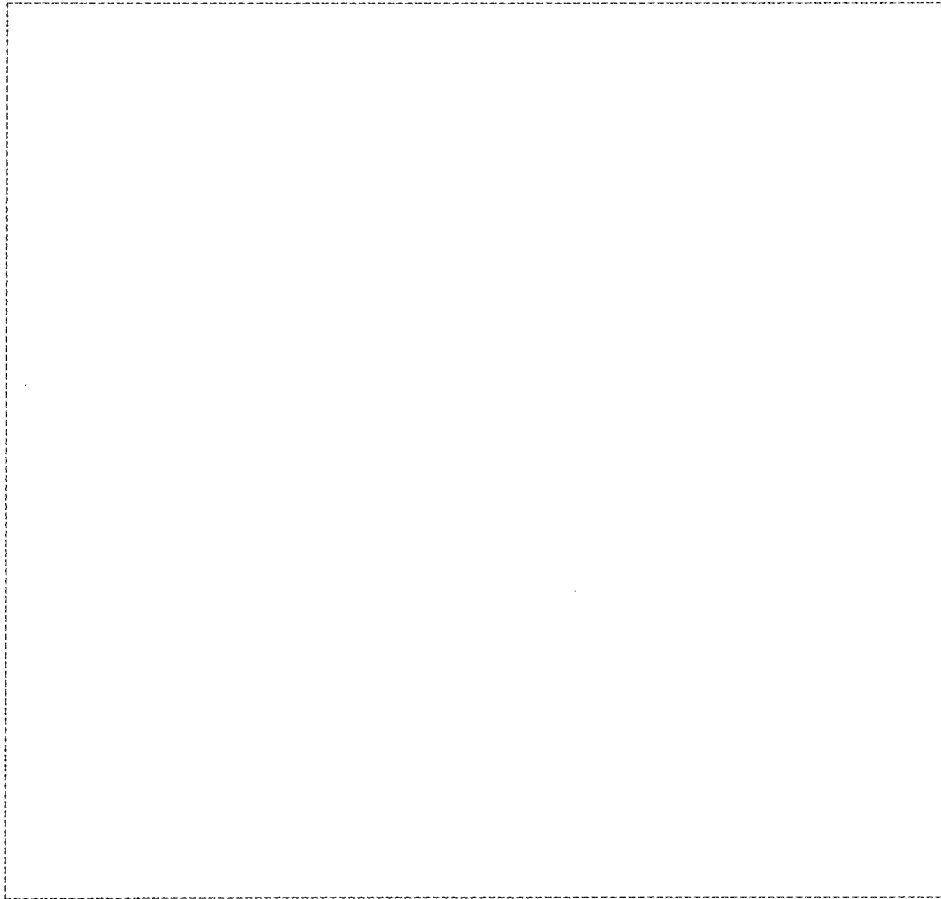


Fig. 4